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10/675,049

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US Patents Full-Text Database
US OCR Full-Text Database
EPO Abstracts Database
JPO Abstracts Database
Derwent World Patents Index
IBM Technical Disclosure Bulletins

Search: L11

Search History

DATE: Saturday, September 25, 2004 [Printable Copy](#) [Create Case](#)

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side by side

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result set

DB=USPT; PLUR=YES; OP=ADJ

<u>L11</u>	L8 and measuring	2	<u>L11</u>
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<u>L7</u>	L2 and (gas near2 flow)	52	<u>L7</u>
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1. Document ID: US 6742701 B2

L11: Entry 1 of 2

File: USPT

Jun 1, 2004

US-PAT-NO: 6742701

DOCUMENT-IDENTIFIER: US 6742701 B2

TITLE: Bump forming method, presoldering treatment method, soldering method, bump forming apparatus, presoldering treatment device and soldering apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KINIC	Drawn D
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2. Document ID: US 6184049 B1

L11: Entry 2 of 2

File: USPT

Feb 6, 2001

US-PAT-NO: 6184049

DOCUMENT-IDENTIFIER: US 6184049 B1

TITLE: Method for fabricating compound semiconductor epitaxial wafer and vapor phase growth apparatus using the same

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KINIC	Drawn D
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Clear	Generate Collection	Print	Fwd Refs	Bkwd Refs	Generate OACCS
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Terms	Documents
L8 and measuring	2

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Search Results - Record(s) 1 through 5 of 5 returned.

1. Document ID: US 6566199 B2

L10: Entry 1 of 5

File: USPT

May 20, 2003

US-PAT-NO: 6566199

DOCUMENT-IDENTIFIER: US 6566199 B2

TITLE: Method and system for forming film, semiconductor device and fabrication method thereof

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KWIC	Drawn D
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2. Document ID: US 6074202 A

L10: Entry 2 of 5

File: USPT

Jun 13, 2000

US-PAT-NO: 6074202

DOCUMENT-IDENTIFIER: US 6074202 A

TITLE: Apparatus for manufacturing a semiconductor material

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KWIC	Drawn D
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3. Document ID: US 4982693 A

L10: Entry 3 of 5

File: USPT

Jan 8, 1991

US-PAT-NO: 4982693

DOCUMENT-IDENTIFIER: US 4982693 A

TITLE: Semiconductor vapor phase growing apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KWIC	Drawn D
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4. Document ID: US RE33326 E

L10: Entry 4 of 5

File: USPT

Sep 11, 1990

US-PAT-NO: RE33326

DOCUMENT-IDENTIFIER: US RE33326 E

TITLE: Semiconductor vapor phase growing apparatus

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Claims](#) | [KMC](#) | [Drawn Ds](#)

5. Document ID: US 4430959 A

L10: Entry 5 of 5

File: USPT

Feb 14, 1984

US-PAT-NO: 4430959

DOCUMENT-IDENTIFIER: US 4430959 A

TITLE: Semiconductor vapor phase growing apparatus

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Claims](#) | [KMC](#) | [Drawn Ds](#)

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L7 and detecting	5

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1. Document ID: US 6742701 B2

L9: Entry 1 of 6

File: USPT

Jun 1, 2004

US-PAT-NO: 6742701

DOCUMENT-IDENTIFIER: US 6742701 B2

TITLE: Bump forming method, presoldering treatment method, soldering method, bump forming apparatus, presoldering treatment device and soldering apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KM/C	Drawn D
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2. Document ID: US 6482762 B1

L9: Entry 2 of 6

File: USPT

Nov 19, 2002

US-PAT-NO: 6482762

DOCUMENT-IDENTIFIER: US 6482762 B1

TITLE: NOx conversion catalyst rejuvenation process

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KM/C	Drawn D
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3. Document ID: US 6379416 B1

L9: Entry 3 of 6

File: USPT

Apr 30, 2002

US-PAT-NO: 6379416

DOCUMENT-IDENTIFIER: US 6379416 B1

TITLE: Method and device for melt-treating incineration residue containing salts

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KM/C	Drawn D
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4. Document ID: US 6184049 B1

L9: Entry 4 of 6

File: USPT

Feb 6, 2001

US-PAT-NO: 6184049

DOCUMENT-IDENTIFIER: US 6184049 B1

TITLE: Method for fabricating compound semiconductor epitaxial wafer and vapor phase growth apparatus using the same

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Search](#) | [Print](#) | [Email](#) | [Claims](#) | [KIDC](#) | [Drawn Ds](#)

5. Document ID: US 5308810 A

L9: Entry 5 of 6

File: USPT

May 3, 1994

US-PAT-NO: 5308810

DOCUMENT-IDENTIFIER: US 5308810 A

TITLE: Method for treating contaminated catalyst

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Search](#) | [Print](#) | [Email](#) | [Claims](#) | [KIDC](#) | [Drawn Ds](#)

6. Document ID: US 5294242 A

L9: Entry 6 of 6

File: USPT

Mar 15, 1994

US-PAT-NO: 5294242

DOCUMENT-IDENTIFIER: US 5294242 A

TITLE: Method for making metal powders

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Search](#) | [Print](#) | [Email](#) | [Claims](#) | [KIDC](#) | [Drawn Ds](#)

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1. Document ID: US 6742701 B2

L6: Entry 1 of 8

File: USPT

Jun 1, 2004

US-PAT-NO: 6742701

DOCUMENT-IDENTIFIER: US 6742701 B2

TITLE: Bump forming method, presoldering treatment method, soldering method, bump forming apparatus, presoldering treatment device and soldering apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KMPC	Drawn D
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2. Document ID: US 6482762 B1

L6: Entry 2 of 8

File: USPT

Nov 19, 2002

US-PAT-NO: 6482762

DOCUMENT-IDENTIFIER: US 6482762 B1

TITLE: NO_x conversion catalyst rejuvenation process

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KMPC	Drawn D
------	-------	----------	-------	--------	----------------	------	-----------	--------	------	---------

3. Document ID: US 6379416 B1

L6: Entry 3 of 8

File: USPT

Apr 30, 2002

US-PAT-NO: 6379416

DOCUMENT-IDENTIFIER: US 6379416 B1

TITLE: Method and device for melt-treating incineration residue containing salts

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KMPC	Drawn D
------	-------	----------	-------	--------	----------------	------	-----------	--------	------	---------

4. Document ID: US 6184049 B1

L6: Entry 4 of 8

File: USPT

Feb 6, 2001

US-PAT-NO: 6184049

DOCUMENT-IDENTIFIER: US 6184049 B1

TITLE: Method for fabricating compound semiconductor epitaxial wafer and vapor phase growth apparatus using the same

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Abstract](#) | [Claims](#) | [KIN/C](#) | [Drawn](#) | [Dscr](#)

5. Document ID: US 5925165 A

L6: Entry 5 of 8

File: USPT

Jul 20, 1999

US-PAT-NO: 5925165

DOCUMENT-IDENTIFIER: US 5925165 A

TITLE: Process and apparatus for the 3-stage treatment of solid residues from refuse incineration plants

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Abstract](#) | [Claims](#) | [KIN/C](#) | [Drawn](#) | [Dscr](#)

6. Document ID: US 5308810 A

L6: Entry 6 of 8

File: USPT

May 3, 1994

US-PAT-NO: 5308810

DOCUMENT-IDENTIFIER: US 5308810 A

TITLE: Method for treating contaminated catalyst

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7. Document ID: US 5294242 A

L6: Entry 7 of 8

File: USPT

Mar 15, 1994

US-PAT-NO: 5294242

DOCUMENT-IDENTIFIER: US 5294242 A

TITLE: Method for making metal powders

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8. Document ID: US 3608609 A

L6: Entry 8 of 8

File: USPT

Sep 28, 1971

US-PAT-NO: 3608609

DOCUMENT-IDENTIFIER: US 3608609 A

TITLE: HEAT-EXCHANGING METHOD AND APPARATUS

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Terms

Documents

L5 and discharge

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